

IN THE CLAIMS

Please amend the claims as follows:

Claim 1-10 (Cancelled).

Claim 11 (Previously Presented): A substrate processing apparatus comprising:
a processing vessel that defines a processing space therein;
a heater portion that heats a substrate introduced into the processing space to a predetermined temperature;
a transparent case made of quartz, the transparent case including a cylinder portion and a top plate for containing the heater portion;
a heater plate mounted on the top plate of the transparent case; and
a holding member for holding the substrate at a position spaced from and opposite to the heater plate.

Claim 12 (Previously Presented): The substrate processing apparatus as claimed in claim 11, further comprising:
a depressurizing part for depressurizing an internal space of the processing vessel and an internal space of the transparent case at a same time.

Claim 13 (Previously Presented): The substrate processing apparatus as claimed in claim 11, further comprising:
a heat reflecting member provided below the heating element for upwardly reflecting heat from the heating element.

Claim 14 (Previously Presented): The substrate processing apparatus as claimed in claim 13, wherein the heat reflecting member is clamped below the heating element in an opposing state.

Claim 15 (Previously Presented): The substrate processing apparatus as claimed in claim 11, further comprising:

a gas injection part for injecting a gas from one side of the processing vessel to the substrate held by the holding member; and

an evacuation port provided at another side of the processing vessel for evacuating the gas passed through the substrate.

Claim 16 (Previously Presented): The substrate processing apparatus as claimed in claim 11, further comprising:

an ultraviolet source for irradiating ultraviolet rays to the processing space.

Claim 17 (Previously Presented): The substrate processing apparatus as claimed in claim 16, wherein the ultraviolet source is arranged to irradiate ultraviolet rays to an area half of the processing space.

Claim 18 (Previously Presented): The substrate processing apparatus as claimed in claim 11, wherein the transparent case includes a support bridge portion extending across the inside of the cylinder portion.

Claim 19 (New) The substrate processing apparatus as claimed in claim 11, wherein the holding member includes:

a plurality of arm portions configured to support the substrate, and
an axis having one end supporting the plural arm portions and another end inserted
into the transparent case.

Claim 20 (New) The substrate processing apparatus as claimed in claim 19, further
comprising a rotational drive part configured to rotatively drive the axis of the holding
member.